

ISSN: 2350-0328

International Journal of Advanced Research in Science, Engineering and Technology

Vol. 8, Issue 4 , April 2021

Construction of graph models of multiparameter optoelectronic converters of liquid turbidity

ShipulinYu.G., Ergashev O.M., Usmanov J.K., Jabbarov Z.R., To'ychiboyev A.E.

Professor, Department of Information Processing and Control Systems, Tashkent State Technical University, Tashkent, Uzbekistan

Assistant Professor, Department of Information technologies, Tashkent University of information technologies, Fergana, Uzbekistan

Deputy Head of the Department of the Chirchik Higher Tank Command Engineering School, Chirchik, Uzbekistan

Assistant Professor, Military Training Center, National University of Uzbekistan, Tashkent, Uzbekistan Student, Department of Programming Engineering, Tashkent University of information technologies, Fergana, Uzbekistan

ABSTRACT: The article deals with the issues of constructive construction and graph models of multipara meter optoelectronic converters of concentration and turbidity of liquids. It is shown that the graph method of analysis makes it possible to visually display the structural property and inter-chain connections of optoelectronic converters.

I. INTRODUCTION

Optoelectronic primary converters are very effective for obtaining information about linear and angular displacements, liquid level, concentration and a number of other technological quantities [1, 2].

The designs of optoelectronic converters are very diverse. In the construction shown in fig. 1, a, the input value X_{BX} — displacement of the liquid level 4 - causes a change in the distribution of the luminous flux Φ_o along with the fiber and the illumination E_o of the radiation receiver (PI) 3. In another design (see Fig . 1.6 A_{BX} — change in the concentration of the liquid (or gas) 5 - also changes the distribution of the luminous flux Φ_o along with the fiber 2 and the illumination PI 3.

In these structures, one can distinguish circuits of various physical nature: electrical (power supply and measurement), optical (transformation), mechanical (input value), etc. In any of these circuits, generalized values of impact (voltage) U_i and reactions (current) I_i , as well as resistance parameters R_i and conductivity G_i .

II. METHODOLOGY

Based on the concepts of geometrical optics in relation to the distribution of the luminous flux along a hollow fiber, we use a formal analogy between the quantities of electrical and optical nature [1], according to which illumination is used as an analogue of the voltage in the optical circuit $U_0 = E_0$ as a current - luminous flux $I_o = \Phi_o$, resistance —

$$R=K_{x}L/S,$$
(1)

and conductivity ----

 $G=1/R0=K_xL/S,$ (2)

Where K_x — absorption coefficient; L, S — length and cross-sectional area of a hollow fiber; R, R0—resistance of the longitudinal and transverse sections of the conversion circuit.

The existing methods for analyzing optoelectronic converters are very complex and involve cumbersome calculations, which do not allow effective analysis of existing structures and the development of new ones.



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International Journal of Advanced Research in Science, Engineering and Technology

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In our opinion, the graph method of analysis is very promising, which clearly displays the structural properties of optoelectronic converters and allows resorting to machine methods of analysis and synthesis of structures and distributed circuits. The analysis of the principles of constructing converters in the language of graphs is reduced to the procedure for transforming an initial graph consisting of a single arc outgoing from a point X_{BX} (vertices - source) and entering the point U_{JBBJX} (the vertex is a sink) into the desired decision graph. The original two-vertex graph, by forming new vertices and arcs, is transformed into the sought-for solution graph of a set of paths corresponding to a set of construction principles.

The graph model shown in Fig. 1, v, contains the following subgraphs (paths): $U_{31} \rightarrow I_{31}$ —Radiation source power circuit; $\Phi_0 \rightarrow E_0$ — conversion chain;

 $U_{_{32}} \rightarrow I_{_{32}}$ —power supply circuit of the measuring circuit and $I_{_{32}} \rightarrow U_{_{3BbIX}}$. The indicated paths refer to circuits of the same physical nature and are characterized by the product of the circuit function T_i per parameter Π_i . Second group of chains — interchain paths: $I_{_{31}} \rightarrow \Phi_3$, $E_0 \rightarrow U_{_{3BbIX}}$, the third - the ways of influence of the input quantity $X_{_{BX}} \rightarrow \Phi_0$, $X_{_{BX}} \rightarrow E_0 X_{_{BX}} \rightarrow U_{_{3BbIX}}$.



Fig. 1. Physical (a, b) and graph (c) model of the device:

1 — radiation source; 2 — light guide; 3 — radiation receiver; 4 — liquid; 5 — cavity of the light guide Thus, this graph model allows us to identify the following construction principles:

1. $X_{BX} \rightarrow \Phi_0 \rightarrow E_0 \rightarrow X_{BMX}$. This principle is associated with exposure to the input variable X_{ex} on chain link function K (I_{31}, Φ_0), those. on the process of converting electric current into a luminous flux. The function transformed based on the graph model has the form

$$U_{3 \text{ BMX}} = U_{31} T_{31} \Pi_{31} K (X_{\text{BX}}, K(I_{31}, \Phi_0)) T_0 \Pi_0 K (E_0 T_{33} \Pi_{33}) T_{32} \Pi_{32} X_{\text{BX}}.$$
(3)

2. $X_{BX} \rightarrow E_0 \rightarrow X_{BMX}$. This principle of action is associated with exposure X_{BX} on the transformation process $\Phi_0 \rightarrow E_0$, what is displayed by the circuit function $T_0\Pi_0$. It is widespread and implemented by changing the absorption coefficients K_x and reflections p, violation of total internal reflection (TIR), moving the screen, and other methods. The transformation function is

 $U_{\mathfrak{B}_{\mathsf{B}\mathsf{B}\mathsf{I}\mathsf{X}}} = U_{\mathfrak{H}}\mathsf{T}_{\mathfrak{H}}\mathsf{T}_{\mathfrak{H}}\mathsf{\Pi}_{\mathfrak{H}}\mathsf{K}(I_{\mathfrak{H}}, \Phi_0)\mathsf{K}(X_{\mathsf{X}\mathsf{B}}, \mathsf{T}_0\mathsf{\Pi}_0)X_{\mathsf{B}\mathsf{X}}\mathsf{K} \times (E_0, \mathsf{T}_{\mathfrak{H}}\mathsf{\Pi}_{\mathfrak{H}})U_{\mathfrak{H}}\mathsf{\Pi}_{\mathfrak{H}}U_{\mathfrak{H}U}U_{\mathfrak{H}}U_{\mathfrak{H}}U_{\mathfrak{H}}U_{\mathfrak{H}U_\mathfrak{H}UU_\mathfrak{H}UU_\mathfrak{H}UU_\mathfrak{H}UU_\mathfrak{H}UU_\mathfrak{$

3. $X_{BX} \rightarrow U_{BLIX}$. This principle is characterized by the impact X_{BX} on the current conversion process $I_{32B}U_{3BLIX}$ in the measuring chain, which is displayed by the inter-chain function $K(E_0, T_{33}, \Pi_{33})$. The transformation function is

 $U_{3 \text{ BMX}} = U_{31} T_{31} \Pi_{31} K(I_{31}, \Phi_0) T_0 \Pi_0 K(X_{BX} K(E_0 T_{33} \Pi_{33})) T_{32} \Pi_{32} U_{32} X_{BX}.$ (5) To analyze transformation functions (3) - (5), it is necessary to determine specific expressions for the

communication functions $K(E_0 T_{33}\Pi_{33}) \times K(I_{31}\Phi_0)$ and $K(X_{xB}, T_0\Pi_0)$ circuit functions T_{31}, T_{32}, T_0 and parameters $\Pi_{31}, \Pi_{32}, \Pi_{01}, T_{33}$. Communication function $K(I_{31}, I_0)$, and $T_{31}\mu\Pi_{31}$ are determined by the types of radiation source, which can be LEDs, lasers, incandescent lamps, etc. Circuit function T_{32} and parameter Π_{32} are determined by the types of power supply of the measuring circuit; for a simple concentrated electrical circuit, their values are: $T_{32} = 1, \Pi_{32} = G_2$.

The essential nodes of the considered converters are the influence circuits of the input quantity X_{BX} and optical voltage E_o on the parameter of the sensitive element $T_{33}\Pi_{33}$, which are determined by communication functions $K(X_{XB}, T_0\Pi_0)$ and $K(E_0, T_{33}, \Pi_{33})$.



ISSN: 2350-0328

International Journal of Advanced Research in Science, Engineering and Technology

Vol. 8, Issue 4 , April 2021



III. CONCLUSION

In the considered converters, the transformation function can be determined if the nature of the distribution is known $\Phi_0(E_0)$ along the fiber chainThis problem is also effectively solved on the basis of the graph model of the distributed optical circuit of the converter (Fig. 2). The nodes of the model display the values of the illumination E_{oij} and the branches $A_{ij}B_{ij}C_{ij}$, D_{ij} are found from the expressions [3]

$$A_{ij} = \frac{1}{R_{ij} \left(\frac{1}{R_{ij}} + \frac{1}{R\phi_{ij}} + \frac{1}{R_{j, i-1}} + \frac{1}{R\phi_{j-1, i}}\right)},$$

$$B_{ij} = \frac{1}{R_{ij} \left(\frac{1}{R_{ij}} + \frac{1}{R\phi_{j, i+1}} + \frac{1}{R_{j, i+1}} + \frac{1}{R\phi_{j-1, i+1}}\right)},$$

$$C_{ij} = \frac{1}{R\phi_{j, i} \left(\frac{1}{R\phi_{j, i}} + \frac{1}{R_{j+1, i}} + \frac{1}{R_{j+1, i+1}} + \frac{1}{R\phi_{j+1, i}}\right)},$$

$$D_{ij} = \frac{1}{R\phi_{ij} \left(\frac{1}{R\phi_{ji}} + \frac{1}{R_{ij}} + \frac{1}{R_{j, i-1}} + \frac{1}{R\phi_{j-1, i}}\right)},$$

The distributions E_{0ij} are determined on the basis of the ASPRP program complex [3], developed on the basis of the graph model (see Fig. 2).

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